

The listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1. (Previously Amended) A laser irradiation apparatus comprising:
  - a beam generating unit for emitting a laser beam;
  - a cylindrical lens group for dividing the emitted laser beam in a first direction, said cylindrical lens group comprising a plurality of cylindrical lenses queuing in said first direction, each of the cylindrical lenses extending in a second direction which is vertical to said first direction;
  - an optical system for overlapping divided laser beams; and
  - a slit located between said beam generating unit and said cylindrical lens group, for making edges of the emitted laser beam straight lines extending parallel to said second direction of each cylindrical lens.
2. (Previously Presented) A laser irradiation apparatus comprising:
  - a beam generating unit for emitting a laser beam;
  - a cylindrical lens group for dividing the emitted laser beam in a width direction, said cylindrical lens group comprising a plurality of cylindrical lenses queuing in said width direction, each of the cylindrical lenses extending in a longitudinal direction which is vertical to said width direction; and
  - an optical system for overlapping divided laser beams,
  - wherein a width of said cylindrical lens group is narrower than a width of the emitted laser beam.
3. (Currently Amended) A laser irradiation apparatus comprising:
  - a beam generating unit for emitting a laser beam;

a cylindrical lens group for dividing the emitted laser beam in a first direction, said cylindrical lens group comprising ~~a plurality a number n~~ of cylindrical lenses queuing in said first direction, each of the cylindrical lenses extending in a second direction; and  
an optical system for overlapping divided laser beams,  
wherein the first and nth cylindrical lenses located at outer sides of the cylindrical lens group are shielded from the laser beam.

4. (Previously Presented) An apparatus according to claim 1, wherein said overlapped laser beam has a longitudinal shape extending in the second direction.

5. (Previously Presented) An apparatus according to claim 2, wherein said overlapped laser beam has a longitudinal shape extending in the longitudinal direction.

6. (Currently Amended) An apparatus according to claim 3, wherein the first and nth cylindrical lenses located at outer sides of the cylindrical lens group comprise quartz ground glass.

7. (Previously Presented) A laser irradiation apparatus comprising:  
a beam generating unit for emitting a laser beam such that a cross section of said laser beam extends in both width and longitudinal directions;  
a cylindrical lens group for dividing said emitted laser beam in said width direction, said cylindrical lens group comprising a plurality of cylindrical lenses queuing in said width direction, each of the cylindrical lenses extending in said longitudinal direction;  
an optical system for overlapping divided laser beams; and  
a slit located between said beam generating unit and said cylindrical lens group, for making at least an edge of the emitted laser beam a straight line which is parallel to said longitudinal direction of each cylindrical lens.

8. (Previously Presented) An apparatus according to claim 7, further comprising a means for irradiating the overlapped laser beam to a substrate.

9. (Previously Presented) An apparatus according to claim 8, wherein said substrate is selected from the group consisting of a glass substrate, a quartz substrate, a ceramic substrate, a semiconductor substrate, a plastic substrate, and an organic resin substrate.

10. (Previously Presented) A laser irradiation apparatus comprising:  
a beam generating unit for emitting a laser beam such that a cross section of said laser beam extends in both width and longitudinal directions;  
a cylindrical lens group for dividing said emitted laser beam in said width direction, said cylindrical lens group comprising a plurality of cylindrical lenses queuing in said width direction, each of the cylindrical lenses extending in said longitudinal direction;  
an optical system for overlapping divided laser beams; and  
a slit located between said beam generating unit and said cylindrical lens group, for making at least one longitudinal edge of the emitted laser beam a straight line which is vertical to said width direction of said cylindrical lens group.

11. (Previously Presented) An apparatus according to claim 10, further comprising a means for irradiating the overlapped laser beam to a substrate.

12. (Previously Presented) An apparatus according to claim 11, wherein said substrate is selected from the group consisting of a glass substrate, a quartz substrate, a ceramic substrate, a semiconductor substrate, a plastic substrate, and an organic resin substrate.

13. (Currently Amended) A laser irradiation apparatus comprising:  
a beam generating unit for emitting a laser beam such that a cross section of  
said laser beam extends in both width and longitudinal directions;  
a cylindrical lens group for dividing said laser beam in said width direction, said  
cylindrical lens group comprising a plurality a number n of cylindrical lenses; and  
an optical system for overlapping divided laser beams,  
wherein the first and nth cylindrical lenses located at outer sides of the cylindrical  
lens group are shielded from the laser beam for making edges of the emitted laser  
beam straight lines extending in said longitudinal direction.
14. (Currently Amended) An apparatus according to claim 13, wherein the first  
and nth cylindrical lenses located at outer sides of the cylindrical lens group comprise  
quartz ground glass.

15. (Previously Presented) An apparatus according to claim 13, further  
comprising a means for irradiating the overlapped laser beam to a substrate.

16. (Previously Presented) An apparatus according to claim 15, wherein said  
substrate is selected from the group consisting of a glass substrate, a quartz substrate,  
a ceramic substrate, a semiconductor substrate, a plastic substrate, and an organic  
resin substrate.

17. (Previously Presented) An apparatus according to claim 1 further  
comprising a stage for holding a substrate having a semiconductor film thereon,  
wherein said semiconductor film is crystallized by irradiating with the laser beam.

18. (Previously Presented) An apparatus according to claim 1 wherein said slit  
comprising at least one of the group consisting of glass, quartz, ceramic, and metal.

19. (Previously Presented) An apparatus according to claim 1 wherein said optical system for overlapping divided laser beams is a convex lens.

20. (Previously Presented) An apparatus according to claim 1, wherein said laser beam is a harmonic of a laser.

21. (Previously Presented) An apparatus according to claim 2 further comprising a stage for holding a substrate having a semiconductor film thereon, wherein said semiconductor film is crystallized by irradiating with the laser beam.

22. (Previously Presented) An apparatus according to claim 2 wherein said optical system for overlapping divided laser beams is a convex lens.

23. (Previously Presented) An apparatus according to claim 2, wherein said laser beam is a harmonic of a laser.

24. (Previously Presented) An apparatus according to claim 3 further comprising a stage for holding a substrate having a semiconductor film thereon, wherein said semiconductor film is crystallized by irradiating with the laser beam.

25. (Previously Presented) An apparatus according to claim 3 wherein said optical system for overlapping divided laser beams is a convex lens.

26. (Previously Presented) An apparatus according to claim 3, wherein said laser beam is a harmonic of a laser.

27. (Previously Presented) An apparatus according to claim 7 further comprising a stage for holding a substrate having a semiconductor film thereon,

wherein said semiconductor film is crystallized by irradiating with the laser beam.

28. (Previously Presented) An apparatus according to claim 7 wherein said slit comprises at least one of the group consisting of glass, quartz, ceramic, and metal.

29. (Previously Presented) An apparatus according to claim 7 wherein said optical system for overlapping divided laser beams is a convex lens.

30. (Previously Presented) An apparatus according to claim 7, wherein said laser beam is a harmonic of a laser.

31. (Previously Presented) An apparatus according to claim 10 further comprising a stage for holding a substrate having a semiconductor film thereon, wherein said semiconductor film is crystallized by irradiating with the laser beam.

32. (Previously Presented) An apparatus according to claim 10 wherein said slit comprises at least one of the group consisting of glass, quartz, ceramic, and metal.

33. (Previously Presented) An apparatus according to claim 10 wherein said optical system for overlapping divided laser beams is a convex lens.

34. (Previously Presented) An apparatus according to claim 10, wherein said laser beam is a harmonic of a laser.

35. (Previously Presented) An apparatus according to claim 13 further comprising a stage for holding a substrate having a semiconductor film thereon, wherein said semiconductor film is crystallized by irradiating with the laser beam.

36. (Previously Presented) An apparatus according to claim 13 wherein said optical system for overlapping divided laser beams is a convex lens.

37. (Previously Presented) An apparatus according to claim 13, wherein said laser beam is a harmonic of a laser.